

DESCRIPTION

SPHERICAL SINTERED FERRITE PARTICLES, RESIN COMPOSITION FOR
SEMICONDUCTOR ENCAPSULATION COMPRISING THEM AND SEMICONDUCTOR
5 DEVICES PRODUCED BY USING THE SAME

Technical Field

The present invention relates to spherical sintered ferrite particles of good electromagnetic wave shieldability, to a resin composition for semiconductor encapsulation comprising them, which is to be a cured body-forming material having both good electromagnetic wave shieldability and good electric insulation properties, and to a semiconductor device of high reliability produced with the resin composition.

15

Background Art

In general, in a process of producing semiconductor devices, the semiconductor element finished after bonding to a substrate is encapsulated with a molding resin such as a thermosetting resin for preventing it from being in contact with the outside. The molding resin is prepared, for example, by mixing and dispersing a silica powder-based inorganic filler in an epoxy resin. Regarding the method of encapsulation with the molding resin, for example, a transfer molding method has
20
25 been put into practical use, which comprises putting a

semiconductor element bonded to a substrate into a mold, transferring a molding resin thereinto under pressure and curing and molding the molding resin therein.

Heretofore, resin-encapsulated semiconductor devices
5 fabricated by encapsulating a semiconductor element with a molding resin are excellent in point of the reliability, the mass-productibility, and the cost thereof, and have become much used in the art along with ceramic-encapsulated semiconductor devices that comprise ceramics as the constitutive material
10 thereof.

With electric appliances, a problem of electromagnetic compatibility (EMC) has been specifically noted. For example, recent information communication appliances are being toward much more down-sized and function-advanced ones, and for further
15 improving the performance of semiconductor devices to be used in such appliances, the signal amplitude is reduced so as to lower the power consumption. As a result, there is increasing a possibility that even minor high-frequency noises may cause malfunction of semiconductor devices. Accordingly,
20 development of electronic devices not releasing any unnecessary electromagnetic waves or resistant to electromagnetic waves generated around them is being promoted.

In general, when a cured product of a resin composition for semiconductor encapsulation has absorbed electromagnetic
25 waves, then it converts the energy of the waves into heat. The

energy conversion efficiency is correlated with the values of the imaginary part ϵ'' of the complex dielectric constant of the dielectric constant of the cured resin as complex expression, and the imaginary part μ'' of the complex magnetic permeability of the magnetic permeability thereof as complex expression. These values each indicate the dielectric loss and the magnetic loss, respectively, of the incident electromagnetic energy; and when these values are larger, then the energy conversion efficiency is higher, and therefore the electromagnetic wave shieldability is higher.

One method of solving the above-mentioned electromagnetic interference problem is proposed, which comprises building a semiconductor element-containing integrated circuit device in a package case equipped with a package base and a package cap formed of ferrite or of a substance having ferrite-corresponding characteristics followed by airtightly encapsulating it therein so as to make the case absorb electromagnetic waves inside and outside it (see Patent Reference 1).

Also proposed is a resin-encapsulated semiconductor device, which comprises a semiconductor element bonded onto a die pad and a wire connected to the semiconductor element and a lead, and in which the wire, the semiconductor element and a part of the lead are encapsulated with a magnetic resin (see Patent Reference 2). In this case, the surface of the

semiconductor device is coated with a ferrite-dispersed magnetic resin to form a two-layered resin-encapsulated structure, or ferrite is used in place of the silica particles to be used as a filler in the molding resin, thereby forming a one-layered
5 resin-encapsulated structure.

Also proposed is a semiconductor package for casing a semiconductor element and other elements therein, of which the semiconductor package body is formed of a magnetic powder-mixed plastic resin (see Patent Reference 3). The plastic resin
10 comprises a magnetic powder such as ferrite or amorphous alloy mixed therein, in which the amount of the magnetic powder is preferably from 30 to 60 % by weight or so. If the amount is smaller than 30 % by weight, then the resin may be ineffective for preventing electromagnetic noises; but even if larger than
15 60 % by weight, the effect of the magnetic powder is saturated.

Also proposed is a semiconductor device comprising a semiconductor part, a wire metal substrate to which the part is bonded and a molding resin to directly cover the part and the necessary area of the metal substrate, in which the molding
20 resin comprises an organic resin and from 35 to 95 % by weight of a ferrite powder added thereto, and the thermal expansion coefficient of the molding resin is from 14 to 20 ppm/°C (see Patent Reference 4). The molding resin may comprise an epoxy resin and a substance of a formula, MFe_2O_4 or $MO \cdot nFe_2O_3$ (wherein
25 M is a divalent metal, and n is an integer) added thereto as

a ferrite powder.

Also proposed is a resin composition for semiconductor encapsulation comprising a thermosetting epoxy resin, a phenolic resin-based curing agent for the epoxy resin, a silica powder and a magnetic powder serving as a filler for the epoxy resin, wherein the mean particle size of the silica powder is smaller than that of the magnetic powder (see Patent Reference 5). This is characterized in that the magnetic powder is ferrite of which the mean particle size is from 10 to 50 μm and the largest particle size is at most 200 μm .

Also proposed is an epoxy resin composition comprising, as the indispensable ingredients thereof, (A) an epoxy resin, (B) a curing agent, (C) a magnetic powder and (d) a curing accelerator, in which the magnetic powder (C) has a relative magnetic permeability of from 50 to 3000 and its content is from 30 to 90 % by volume of the overall epoxy resin composition (see Patent Reference 6). Preferably, the relative magnetic permeability of the magnetic powder (C) is higher; and if it is less than 50, then the complex magnetic permeability of the resin composition is low and the electromagnetic wave shieldability thereof may be insufficient. For the magnetic powder (C), preferred is a ferrite-based powder; and Ni-Zn-based ferrite or Mn-Zn-based ferrite may be preferably used in spinel type, and Zr-Mn-based ferrite or Ti-Mn-based ferrite may be preferably in magnetoplumbite type.

Patent Reference 1	JP-A-64-41248
Patent Reference 2	JP-A-3-23654
Patent Reference 3	JP-A-6-151626
Patent Reference 4	JP-A-11-40708
5 Patent Reference 5	JP-A-2002-363382
Patent Reference 6	JP-A-2003-128880

Disclosure of the Invention

Problems that the Invention is to Solve

10 However, the semiconductor package with ferrite in Patent Reference 1 is difficult to work and is not practicable in point of its cost. Therefore, a method of semiconductor encapsulation with ferrite is desired, which is simple and easy and which is more effective and more reliable for solution of electromagnetic
15 interference problems.

 In Patent Reference 2, a semiconductor device having a one-layered resin structure is easily produced, using ferrite as a filler for the molding resin, and the device is prevented from malfunctioning with electromagnetic noises. In this,
20 however, since the ferrite-containing resin is in direct contact with the semiconductor element, the resin composition that contains an ordinary ferrite having many soluble ions is problematic in its reliability. Further, also in Patent Reference 3, the device is problematic in its reliability since
25 a semiconductor element and others are encapsulated through

direct molding with a magnetic substance-mixed plastic material.

In Patent Reference 4, the reliability is increased by the use of a molding resin containing from 35 to 95 % by weight of a ferrite powder added thereto and having a thermal expansion
5 coefficient of from 14 to 20 ppm/°C. However, this reference does not disclose the moldability and the dielectric breakdown property of the resin as well as the short-circuit test result with the resin under a load of bias voltage applied thereto, in which, therefore, there are some problems in point of the
10 moldability of the molding resin having a high ferrite content and of the reliability thereof under a load of bias voltage applied thereto.

In Patent Reference 5, the inventors specifically noted the moldability of a ferrite powder-mixed molding resin and the
15 risk of malfunction through current leakage owing to the contact between a semiconductor element and the cured product of the molding resin, and proposed a resin composition for semiconductor encapsulation that contains a specific silica powder and a specific ferrite-based magnetic powder, as so mentioned
20 hereinabove; however, the resin composition is still unsatisfactory in point of the reliability thereof in practical use.

In Patent Reference 6, proposed is an epoxy resin composition for semiconductor encapsulation, which contains a
25 magnetic powder having a high magnetic permeability of from 50

to 3000. However, of ferrite-based powders that are said to be preferred for use therein, the magnetic permeability of those having a high magnetic permeability may be at most 30 or so; and, in fact, therefore, the powders are far from those capable
5 of satisfying the requirement of the invention in this reference. In this, in addition, nothing is referred to relating to the reliability of ferrite, and its use is problematic.

The molding resin in a resin composition for semiconductor encapsulation must have a low viscosity up to the molding
10 temperature thereof because of its requirement for low-pressure transfer moldability, and it is required to have high flowability. In such a molding resin system, ground Mn-Zn-based ferrite and Ni-Zn-based ferrite prepared by mechanically grinding ordinary ferrite ingots are unsatisfactory for increasing the filling
15 ratio with the ferrite particles therein for the purpose of increasing the magnetic permeability of the resulting resin. Specifically, it is necessary to optimize the shape and the particle size of ferrite particles to be in a resin composition for semiconductor encapsulation as a filler therein, and to lower
20 the ionic impurity content of the ferrite particles for increasing the reliability of resin-encapsulated semiconductor devices.

The invention has been made in consideration of the situation as above, and its object is to provide spherical
25 sintered ferrite particles useful as a filler for a resin

composition for semiconductor encapsulation, to provide a resin composition for semiconductor encapsulation comprising it, which has good electromagnetic wave shieldability, good moldability and high reliability, and to provide a semiconductor
5 device encapsulated with the resin composition.

Means for Solving the Problems

To attain the object as above, the present invention has the following constitutions.

1. Spherical sintered ferrite particles having the
10 following properties (a) to (c):

(a) the soluble ion content of the particles is 5 ppm or less;

(b) the mean particle size of the particles is from 10 to 50 μm ;

(c) the crystal structure of the particles by X-ray
15 diffractiometry is a spinel structure.

2. Spherical sintered ferrite particles as described in the item 1, which have the following property (d) in addition to the properties (a) to (c):

20 (d) the particle size distribution of the spherical sintered ferrite particles has a peak in each of a particle size range of from 5 to 15 μm and a particle size range of from 20 to 50 μm .

25 3. Spherical sintered ferrite particles as described in

the item 1 or 2, which are an oxide of Fe and at least one metal element M selected from the group consisting of Mg, Zn, Ni, Mn and Cu.

5 4. Spherical sintered ferrite particles as described in the item 3, wherein the molar ratio of the metal element M to Fe (M/Fe) constituting the spherical sintered ferrite particles is within a range of $M/Fe = 1/1.57$ to $1/2.17$.

10 5. Spherical sintered ferrite particles as described in any one of the items 1 to 4, which have a specific surface area by a BET method of from 0.02 to $0.1 \text{ m}^2/\text{g}$.

15 6. Spherical sintered ferrite particles as described in any one of the items 1 to 5, which have a pore volume by a mercury penetration method of 0.2 liter/kg or less.

20 7. A resin composition for semiconductor encapsulation, which comprises a filler containing the spherical sintered ferrite particles of any one of the items 1 to 6, and silica particles.

25 8. The resin composition for semiconductor encapsulation as described in the item 7, wherein the proportion of the filler is from 65 to 80% by volume of the resin composition.

9. The resin composition for semiconductor encapsulation as described in the item 7 or 8, wherein the proportion of the spherical sintered ferrite particles in the filler is at least 50 % by volume of the filler.

5

10. The resin composition for semiconductor encapsulation as described in the item 9, wherein the blend constitution of the filler meets the following (d1) to (d3):

- (d1) the silica particles having a mean particle size of from 5 to 15 μm account for from 4 to 30 % by volume of the filler;
- (d2) the spherical sintered ferrite particles having a mean particle size of from 20 to 50 μm account for from 50 to 93 % by volume of the filler;
- (d3) the silica particles having a mean particle size of from 0.2 to 2 μm account for from 3 to 30 % by volume of the filler.

11. The resin composition for semiconductor encapsulation as described in the item 9, wherein the blend constitution of the filler meets the following (d4) to (d6):

- (d4) the spherical sintered ferrite particles having a mean particle size of from 5 to 15 μm account for from 4 to 30 % by volume of the filler;
- (d5) the spherical sintered ferrite particles having a mean particle size of from 20 to 50 μm account for from 50 to 93 % by volume of the filler;

(d6) the silica particles having a mean particle size of from 0.2 to 2 μm account for from 3 to 30 % by volume of the filler.

12. The resin composition for semiconductor
5 encapsulation as described in any one of the items 7 to 11, wherein the silica particles are spherical silica particles.

13. The resin composition for semiconductor
encapsulation as described in any one of the items 7 to 12, which
10 contains an epoxy resin and a phenolic resin-based curing agent.

14. The resin composition for semiconductor
encapsulation as described in the item 13, which contains a curing
accelerator along with the epoxy resin and the phenolic
15 resin-based curing agent.

15. A semiconductor device produced by encapsulating a
semiconductor element with the resin composition for
semiconductor encapsulation of any one of the items 7 to 14.
20

For the purpose of obtaining a resin composition to be
an encapsulation material which has good electromagnetic wave
shieldability and has good moldability and high reliability,
we, the present inventors have made assiduous studies of
25 essentially the constitutive components of the encapsulation

material. We have specifically noted a spinel-type ferrite which has heretofore been used for imparting electromagnetic wave shieldability to encapsulation materials, and have made a series of studies for obtaining a spinel-type ferrite material having good moldability and high reliability and having good electromagnetic wave shieldability. As a result, we have found that, when spherical sintered ferrite particles (a) having a soluble ion content of at most 5 ppm, (b) having a mean particle size of from 10 to 50 μm , and (c) having a spinel structure as the crystal structure thereof by X-ray diffractometry are used in a resin composition, then the resin composition may effectively express the excellent electromagnetic wave shieldability that the spherical sintered ferrite particles have, that the resin composition may ensure the reliability necessary and indispensable for recent encapsulation materials, that the resin composition may have a low melt viscosity while having a high filling ratio of the filler component therein, that the resin composition may have an increased mechanical strength of the cured product thereof, and that the resin composition may have good moldability; and on the basis of these findings, we have reached the present invention.

Effect of the invention

As above, the invention provides spherical sintered ferrite particles having the above-mentioned properties (a) to (c) and to provide a resin composition for semiconductor

encapsulation that contains a filler comprising the specific, spherical sintered ferrite particles and silica particles. Accordingly, the resin composition has low viscosity and good flowability and has good electromagnetic shieldability; and when
5 the resin composition is used as an encapsulation material, then the resulting semiconductor device has good EMC characteristic.

When the spherical sintered ferrite particles have, in addition to the above-mentioned properties (a) to (c), an additional property (d) that the particle size distribution
10 thereof has a peak in each of a particle size range of from 5 to 15 μm and a particle size range of from 20 to 50 μm , and when the particles of the type are used, then their fillability is further improved and they may have much better flowability and more excellent electromagnetic wave shieldability.

15 When the spherical sintered ferrite particles have a specific surface area by a BET method of from 0.02 to 0.1 m^2/g , then they may have further better flowability.

When the spherical sintered ferrite particles have a pore volume by a mercury penetration method of 0.2 liter/kg or less,
20 then they may have further better flowability.

Brief Description of the Drawings

Fig. 1 is a cross-sectional view showing one example of the semiconductor device of the invention.

25 Fig. 2 is a cross-sectional view showing another example

of the semiconductor device of the invention.

Fig. 3 is a particle size distribution curve of the spherical sintered ferrite particles used in Example 5.

5 Description of Reference Numerals

10 and 20	Semiconductor Device
11 and 21	Substrate
14 and 22	Semiconductor Element
16 and 24	Cured Product

10

Best Mode for Carrying out the Invention

In the invention, specific spherical sintered ferrite particles are obtained, and the most characteristic feature of the invention is that the specific spherical sintered ferrite particles are used in the resin composition for semiconductor encapsulation of the invention. For example, the resin composition may be prepared by formulating an epoxy resin and a phenolic resin-based curing agent, and additionally a curing accelerator and a silica powder, and in general, it is in the form of powder or tablets produced by tableting it.

For the specific spherical sintered ferrite particles, the starting materials are washed with water, then sintered in spheres and thereafter further washed with water; or after sintered in spheres, they may be fully washed to thereby reduce the soluble ion content of the resulting particles to at most

5 ppm. Preferably, the soluble ion content is reduced to at most 1 ppm. Thus reducing the soluble ion content to the lowermost limit may increase the reliability of the resin composition for semiconductor encapsulation that comprises the resulting particles. Specific examples of the soluble ion include Na^+ , PO_4^{3-} , and Cl^- . In case where the soluble ion content is lower than the detection limit, then it is expressed as 0 ppm, and the total amount of the detected ions is computed.

The crystal structure by X-ray diffractionmetry of the specific spherical sintered ferrite particles is a spinel structure. Recently, the operating frequency of semiconductor devices is over a level of 1 GHz, and semiconductor devices must be shielded from unnecessary radio waves of higher frequency. Having such a spinel structure, the ferrite particles may satisfy this requirement. Preferably, the spherical sintered ferrite particles are an oxide of at least one metal element M selected from the group consisting of Mg, Zn, Ni, Mn and Cu, with Fe. Specifically, this is because the electrical resistance of the material for semiconductor encapsulation is required to as high as possible. Also preferably, regarding the composition of the spherical sintered ferrite particles, the molar ratio of the metal element M to Fe constituting the particles is within a range of $\text{M/Fe} = 1/1.57$ to $1/2.17$. Specifically, when the molar ratio of the two oversteps the above range, then the particles could not be sufficiently ferritized and could hardly have

satisfactory magnetic characteristics. On the other hand, when the form of the sintered ferrite particles is not spherical, for example, when the particles have various shapes, then the viscosity of the resin composition may increase and the flowability thereof may worsen.

Preferably, the spherical sintered ferrite particles have a specific surface area by a BET method of from 0.02 to 0.1 m²/g. Also preferably, the particles have a pore volume by a mercury penetration method of 0.2 liter/kg or less. Having such a specific surface area and such a pore volume, the spherical sintered ferrite particles may have an increased degree of sintering and their surface may be smoothed, and therefore the flowability of the resin composition containing them in encapsulation of semiconductor elements is increased. Further, since the number of the pores in the particles is small, it is easy to remove soluble ions from the particles by washing them to a level of 5 ppm or less.

The mean particle size of the specific spherical sintered ferrite particles of the invention must fall within a range of from 10 to 50 μm, more preferably from 15 to 40 μm. Even more preferably, particles having a particle size of 63 μm or more do not substantially exist in the specific spherical sintered ferrite particles of the invention. In order that the resin composition for semiconductor encapsulation of the invention may contain the ferrite particles in an increased filling ratio

and may have good flowability, and in order that the electromagnetic characteristic of the resin composition, μ'' at 1 GHz thereof could be kept high, it is desirable that, in the particle size distribution thereof, the ferrite particles may

5 have a peak within a particle size range of from 5 to 15 μm and a peak within a particle size range of from 20 to 50 μm . More preferably, the spherical sintered ferrite particles to be in the resin composition may have a peak at a particle size of around 10 μm and a peak at a particle size of around 30 μm . For obtaining

10 the spherical sintered ferrite particles having such two peaks in the particle size distribution thereof, for example, herein employable is a method of mixing two types of spherical sintered ferrite particles, or that is, spherical sintered ferrite particles having a mean particle size of from 5 to 15 μm and

15 spherical sintered ferrite particles having a mean particle size of from 20 to 50 μm . The spherical sintered ferrite particles having a particle size of around 10 μm may have a high μ'' at 1 GHz, and they may be effective for improving the electromagnetic wave shieldability of the resin composition for semiconductor

20 encapsulation containing them. The mean particle size and the particle size distribution of the specific spherical sintered ferrite particles mentioned above may be determined, for example, by the use of a laser-diffractometric particle size analyser.

The specific spherical sintered ferrite particles may

25 be produced, for example, as follows: First described is a method

of preparing a starting ferrite powder. Starting materials for it are weighed to be a desired composition, and mixed with stirring in an aqueous solvent to give an aqueous dispersion slurry having a slurry concentration of from 60 to 90 % by weight, and then
5 the slurry is dried by spraying, and thereafter this is heated at 800 to 1300°C or so to produce spherical sintered ferrite particles. The resulting spherical sintered ferrite particles are washed by stirring them in pure water having an electroconductivity of at most 1 μ S/cm in a ratio by volume of
10 about 1/30 (particles/water), for about 30 minutes, and then dried to produce the intended, specific spherical sintered ferrite particles.

The starting ferrite powder that is to be the source of the constitutive elements of the specific spherical sintered
15 ferrite particles of the invention may be an oxide, a hydroxide an oxalate or a carbonate with any of Mg, Zn, Ni, Mn, Cu. The Fe element source may be iron oxide. These element sources may be mixed in a ratio to give the intended ferrite composition.

Regarding the particle morphology thereof, the particles
20 of the starting ferrite powder may have any morphology of cubic, polyhedral, acicular or tabular forms. Preferably, the mean particle size of the starting ferrite powder is from 0.01 to 5.0 μ m, more preferably from 0.1 to 2.0 μ m. When the size is smaller than 0.01 μ m, then the slurry viscosity may be high and
25 accidents may happen in spraying and drying the slurry. On the

other hand, when the size is larger than 5.0 μm , then the surface roughness of the sintered product may increase and the specific surface area thereof may be too large with the result that the filling ratio of the particles in resin compositions could not
5 increase.

In the process of producing the specific spherical sintered ferrite particles, a anticoagulant may be used in the slurry formation step. The anticoagulant may be ordinary surfactant, preferably having a functional group capable of
10 binding to the hydroxyl group that the surfaces of inorganic compound particles and sintered ferrite particles may have. More specifically, it includes sodium polycarboxylates, anionic ammonium polycarboxylates, sodium naphthalenesulfonate. In consideration of the residues of ionic impurities after firing,
15 preferably used herein is a 40 % solution of an anionic ammonium polycarboxylate.

Another production method is described. The starting ferrite powder as above is weighed to be a desired composition, then stirred and mixed in a dry or wet mixing mode,
20 primary-sintered at 800 to 900°C, and then dry-ground or wet-ground to give ferrite crystal particles of from 0.1 to 5.0 μm in size. Next, a slurry that contains the ferrite crystal particles is processed to give an aqueous dispersion slurry having a slurry concentration of from 60 to 90 % by weight, then
25 this is dried by spraying, and thereafter heated at 900 to 1300°C

to give spherical sintered ferrite particles. The resulting spherical sintered ferrite particles are washed by stirring them in pure water having an electroconductivity of at most 1 $\mu\text{S}/\text{cm}$ in a ratio by volume for dilution of about 1/30 (particles/water),
5 for about 30 minutes, and then dried to produce the intended spherical sintered ferrite particles of the invention. In the slurry formation step, the same anticoagulant as that mentioned hereinabove in the production of the starting ferrite powder may also be used.

10 The ferrite crystal particles may have any particle morphology of cubic, polyhedral, acicular or tabular forms. Preferably, the mean particle size of the ferrite crystal particles is from 0.01 to 5.0 μm , more preferably from 0.2 to 3.0 μm . When the size is smaller than 0.01 μm , then the slurry
15 viscosity may be high and accidents may happen in spraying and drying the slurry. On the other hand, when the size is larger than 5.0 μm , then the surface roughness of the sintered product may increase and the specific surface area thereof may be too large with the result that the filling ratio of the particles
20 in resin compositions could not increase.

In producing the spherical sintered ferrite particles of the invention, the slurry is preferably dried by spraying at a slurry concentration of from 50 to 90 % by weight, more preferably from 50 to 80 % by weight. When the concentration
25 is lower than 50 % by weight, then the pore volume of the resulting

particles may increase; but when larger than 90 % by weight, then the slurry viscosity may increase and the resulting particles could hardly keep their spherical form, and in addition, the particle size of the particles may be difficult to control.

5 Though depending on the ferrite composition thereof, the particles may be fired at a temperature of from 800 to 1300°C or so for 1 to 8 hours in the invention. When the particles are fired at a temperature lower than 800°C, then they may be insufficiently ferritized; but when higher than 1300°C, then
10 the sintered particles may fuse together and much thickened and aggregated particles may increase.

 Regarding the blend ratio of the specific spherical sintered ferrite particles in the resin composition for semiconductor encapsulation, the imaginary part μ'' of the complex
15 magnetic permeability of the cured product of the resin composition must be large in order that the cured resin could have an increased electromagnetic wave shielding effect; and for this, the blend ratio of the spherical sintered ferrite particles in the resin composition is preferably at least 32.5 %
20 by volume of the resin composition, more preferably at least 40 % by volume. The uppermost limit of the blend ratio is generally 80 % by volume or so. The uppermost limit is generally within a range within which the flowability of the resin composition could be ensured. If the blend ratio oversteps the
25 uppermost limit, then the flowability of the resin composition

may lower and the resin composition may be difficult to work.

As so mentioned hereinabove, the most characteristic feature of the resin composition for semiconductor encapsulation of the invention is that it contains the specific spherical
5 sintered ferrite particles; and the resin compositions may contain, for example, an epoxy resin and a phenolic resin-based curing agent optionally along with a curing accelerator and a silica powder.

Not specifically defined, the epoxy resin may be any
10 conventional known one that is solid at room temperature (25°C), including, for example, a biphenyl-type epoxy resin, a phenol-novolak-type epoxy resin, a cresol-novolak-type epoxy resin. One or more of these may be in the composition either singly or as combined.

15 Also not specifically defined, the phenolic resin-based curing agent may be any conventional known one that acts as a curing agent for the epoxy resin and is solid at room temperature (25°C), including, for example, phenol-novolak, cresol-novolak, bisphenol A-type novolak, naphthol-novolak and phenol-aralkyl
20 resins. One or more of these may be in the composition either singly or as combined.

The blend ratio of the epoxy resin and the phenolic resin-based curing agent may be so designed that the hydroxyl equivalent in the phenolic resin to one equivalent of the epoxy
25 group in the epoxy resin could be from 0.5 to 1.6, more preferably

from 0.8 to 1.2.

Not specifically defined, the curing accelerator may also be any conventional known one, including, for example, tertiary amines such as 1,8-diazabicyclo(5,4,0)undecene-7, triethylenediamine; imidazoles such as 2-methylimidazole; and phosphorus-containing curing accelerators such as triphenylphosphine, tetraphenylphosphonium tetraphenylborate. One or more of these may be in the composition either singly or as combined.

10 The amount of the curing accelerator to be in the resin composition may be generally from 0.5 to 10 parts by weight (hereinafter simplified to "parts") relative to 100 parts of the phenolic resin-based curing agent therein.

The resin composition for semiconductor encapsulation of the invention may contain, as a filler along with the above-mentioned spherical sintered ferrite particles, silica particles that are heretofore used as a material for semiconductor encapsulation for reducing burrs in molding. Not specifically defined, the blend ratio of the spherical sintered ferrite particles to the silica particles is preferably so designed that the proportion of the spherical sintered ferrite particles is larger for increasing the electromagnetic wave shieldability of the resin composition. More specifically, the blend ratio of the spherical sintered ferrite particles to the silica particles is preferably such that the proportion of the

15
20
25

spherical sintered ferrite particles may be at least 50 % by volume of the whole filler (spherical sintered ferrite particles and silica particles). Also preferably, the total volume of the spherical sintered ferrite particles and the silica particles is from 65 to 80 % by volume of the resin composition. When the total volume is smaller than 65 % by volume, then the linear expansion coefficient of the resin composition for semiconductor encapsulation may increase with the result that the cured resin may crack in thermal cycles owing to the difference in the linear expansion coefficients between the cured resin and semiconductor elements. On the other hand, when the total volume is larger than 80 % by volume, then the flowability of the resin composition for semiconductor encapsulation may lower and the resin composition could hardly encapsulate semiconductor elements with the result that the metal wires to bond semiconductor elements and electrodes may be deformed or broken.

The silica particles for use herein preferably have a mean particle size of from 1 to 40 μm and a largest particle size of at most 200 μm , more preferably a largest particle size of at most 100 μm , even more preferably at most 63 μm . Still more preferably, silica particles having a mean particle size of from 5 to 15 μm and silica particles having a mean particle size of from 0.2 to 2 μm are combined for use herein. Having the constitution makes it possible to increase the filling ratio of the spherical sintered ferrite particles in the resin

composition and to increase the flowability of the resin composition. Describing more in detail, it is desirable that the silica particles having a mean particle size of from 5 to 15 μm account for from 4 to 30 % by volume of the filler, that
5 the spherical sintered ferrite particles having a mean particle size of from 20 to 50 μm account for from 50 to 93 % by volume of the filler, and that the silica particles having a mean particle size of from 0.2 to 2 μm account for from 3 to 30 % by volume of the filler. A part or all of the silica particles having
10 a mean particle size of from 5 to 15 μm may be replaced with the spherical sintered ferrite particles, or that is, they may be replaced with the spherical sintered ferrite particles having a mean particle size of from 5 to 15 μm whereby the electromagnetic wave shieldability of the resin composition may be further
15 enhanced. Like that of the above-mentioned, specific spherical sintered ferrite particles, the mean particle size of the silica particles may be determined, for example, by the use of a laser-diffractometric particle size analyser.

The silica particles may be, for example, spherical fused
20 silica powder, ground silica powder, pulverized silica powder. Especially preferred is spherical fused silica powder, as effective for reducing the melt viscosity of the resin composition for semiconductor encapsulation containing it.

Depending on the use of semiconductor devices and the
25 service environment for them, the resin composition for

semiconductor encapsulation of the invention may contain any other filler added thereto. The additional filler includes, for example, calcium carbonate powder, titanium white, alumina powder, silicon nitride powder; and one or more of these may
5 be in the composition either singly or as combined.

In addition, the resin composition for semiconductor encapsulation may optionally contain any other additives such as stress reducer, pigment, lubricant, coupling agent and flame retardant, if desired.

10 The stress reducer includes silicone compounds such as poly(ethylene glycol)-branched polydimethylsiloxane, and acrylonitrile-butadiene rubber.

The pigment includes carbon black, titanium oxide.

The lubricant includes polyethylene wax, carnauba wax,
15 fatty acid salts.

The coupling agent includes silane-coupling agents such as γ -glycidoxypropyltrimethoxysilane, β -(3,4-epoxycyclohexyl)ethyltrimethoxysilane.

For the flame retardant, a bromoepoxy resin may be used,
20 optionally combined with a flame retardation promoter such as antimony trioxide.

Apart from the above flame retardant, also employable herein are metal hydroxides of the following formula (1). The metal hydroxides have a polyhedral crystal form, differing from
25 conventional hexahedral tabular crystal forms or thin tabular

crystal forms such as flaky forms. More specifically, the metal hydroxides have granular crystal forms approximated to more three-dimensional and spherical forms, for example, having nearly dodecahedral, nearly octahedral or nearly tetrahedral forms, as both the longitudinal side and the lateral side crystal growth of the metal hydroxides is large in the thickness direction thereof (c-axis direction), for example, tabular crystals of metal hydroxides have grown in the thickness direction thereof (c-axis direction) therefore having the polyhedral forms as above.



In formula (1), M is at least one metal atom selected from a group consisting of Mg, Ca, Sn and Ti; Q is at least one metal atom selected from a group consisting of Mn, Fe, Co, Ni, Cu and Zn; and x is a positive number of from 0.01 to 0.5.

The metal hydroxides having such polyhedral crystal forms may be produced, for example, by controlling various conditions in producing metal hydroxides in such a manner that both the longitudinal side and the lateral side crystal growth of the metal hydroxides produced could be large in the thickness direction thereof (c-axis direction) so as to have the desired polyhedral crystal forms of, for example, nearly dodecahedral, nearly octahedral or nearly tetrahedral forms. In general, mixtures of metal hydroxides having such various polyhedral crystal forms may be used herein.

Representative examples of the polyhedral metal hydroxides are $Mg_{1-x}Ni_x(OH)_2$ ($0.01 < x < 0.5$), $Mg_{1-x}Zn_x(OH)_2$ ($0.01 < x < 0.5$). These metal hydroxides are commercially available, for example, as Tateho Chemical Industry's commercial products,
5 EcoMag.

The aspect ratio of the polyhedral metal hydroxides may be generally from 1 to 8, preferably from 1 to 7, more preferably from 1 to 4. The aspect ratio as referred to herein means a ratio of the major diameter to the minor diameter of a metal
10 hydroxide particle. When the aspect ratio is larger than 8, then the melt viscosity of the epoxy resin composition containing the metal hydroxide may increase.

The resin composition for semiconductor encapsulation of the invention may be produced, for example, as follows: An
15 epoxy resin, a phenolic resin-based curing agent, a curing accelerator, spherical sintered ferrite particles, and optionally an inorganic filler such as silica particles and other additives such as stress reducer, pigment, lubricant, coupling agent and flame retardant are blended in a predetermined ratio
20 thereof. Next, the mixture is melt-kneaded and dispersed sufficiently by the use of a hot roll, an extruder, a kneader or the like, for example, at a temperature of 95 to 100°C. Then, the resulting mixture is cooled and ground, and passed through a 10-mesh screen to give a powdery resin composition for
25 semiconductor encapsulation. If desired, it may be

compression-molded into tablets. Through the process of a series of such steps, the resin composition for semiconductor encapsulation having a desired form of the invention may be obtained.

5 Thus obtained, the resin composition for semiconductor encapsulation may be used essentially for encapsulation of even the details of semiconductor elements of semiconductor devices, whereby the semiconductor elements may be protected from physical contact with the outside and may be shielded from electromagnetic
10 waves.

A semiconductor device as resin-molded with the resin composition for semiconductor encapsulation of the invention is described with reference to the drawings attached hereto to show the cross-sectional view thereof.

15 Fig. 1 shows an area-mounted semiconductor device 10, in which the through-holes of the substrate 11 are filled with wires 12. On the substrate 11, formed is an electrode 15 connected to the wires 12, and a semiconductor element 14 is mounted thereon. On the other side of the substrate 11, provided
20 are solder balls 13, and these are electrically connected to the electrode 15 via the wires 12. The semiconductor element 14 is electrically connected to the electrode 15 via a wire bonding 17. In Fig. 1, 16 is a cured product formed of the resin composition for semiconductor encapsulation of the invention,
25 and this encapsulates the semiconductor element 14.

Fig. 2 is a cross-sectional view of another example of a semiconductor device as resin-molded with the resin composition for semiconductor encapsulation of the invention. The semiconductor device 20 is a peripheral terminal-mounted semiconductor device, in which the semiconductor element 22 mounted on the substrate 21 is connected to the electrode 23 via the wire bonding 25. The semiconductor element 22 is wholly resin-molded with the cured product 24 on both surfaces of the substrate 21.

10 The semiconductor devices 10, 20 having the constitutions of Fig. 1 and Fig. 2 may be produced, for example, according to a low-pressure transfer-molding process that comprises putting a substrate 11, 21 with a semiconductor element 14, 22 mounted thereon, into a mold, then transferring a heated resin composition for semiconductor encapsulation into it under low
15 pressure.

One example of the process is described. First, a semiconductor element 14, 22 is disposed on a substrate 11, 21, as connected to an electrode 15, 23 via a wire bonding 17, 25; and this is set in a mold comprising an upper mold part and a lower mold part. Next, a resin composition for semiconductor encapsulation is transferred into the mold under pressure by a plunger, and kept under pressure until it is cured. After cured, the upper mold part and the lower mold part are split
20 off from each other, and thus a semiconductor device 10, 20 is
25

obtained in which the semiconductor element 11, 22 is resin-molded with the cured product 16, 24.

In the semiconductor device 10, 20 thus obtained, the semiconductor element 14, 22 is protected from the outside, and is shielded from electromagnetic waves owing to the magnetic loss of the specific sintered ferrite powder contained in the cured product 16, 24. Accordingly, the semiconductor device is applicable to electronic devices or electronic appliances that require EMC.

10 The invention is described in more detail with reference to the following Examples and Comparative Examples.

Examples

Spherical sintered ferrites were produced as follows:

15 Production of Spherical Sintered Ferrite a

A starting ferrite powder comprising 15 mol% of NiO, 25 mol% of ZnO, 12 mol% of CuO and 48 mol% of Fe₂O₃ and having an overall weight of 4 kg was put into a ball mill along with 2.6 kg of pure water thereinto, and stirred for 20 minutes. Next, 20 g of an anticoagulant, 40 % anionic polyammonium carboxylate (San Nopco's SN Dispersant 5468), and 10 g of a silicone defoaming agent (San Nopco's SN deformer 465) were added thereto and mixed to prepare a slurry. The resulting slurry concentration was 60 % by weight. Next, the slurry was dried by spraying to obtain 25 a granulated powder. In the resulting powder, the starting

particles aggregated into spheres, and the surface roughness level and the surface roughness profile of the starting particles were directly transferred onto the surfaces of the aggregated spheres. Next, the powder was heated at 800°C for 2 hours, and then heated (fired) at 1000°C for 3 hours to obtain surface-smoothed, spherical sintered ferrite particles. Next, these were washed by stirring them twice each for 20 minutes in ion-exchanged water of which the overall amount was 30 times by weight of the particles, and then dewatered and dried, thereby producing spherical sintered ferrite particles having a soluble ion content of at most 5 ppm. Through X-ray diffractionometry, the crystal structure of the particles was a spinel structure.

Production of Spherical Sintered Ferrite b

A starting ferrite powder comprising 15 mol% of NiO, 25 mol% of ZnO, 12 mol% of CuO and 48 mol% of Fe₂O₃ was mixed in wet, then dewatered, and heated (primary-fired) at 800°C for 2 hours according to a conventional process. The resulting ferrite powder was ground in dry to obtain ferrite crystal particles having a mean particle size of 1 μm. Next, 4 kg of the ferrite crystal particles were taken out, and put into 1.3 kg of pure water. Next, 30 g of an anticoagulant, 40 % anionic polyammonium carboxylate (San Nopco's SN Dispersant 5468), and 16 g of a silicone defoaming agent (San Nopco's SN deformer 465) were added thereto, and mixed and stirred to prepare a slurry. The resulting slurry concentration was 75 % by weight. Next,

the slurry was dried by spraying to obtain a granulated powder. In the resulting powder, the ferrite crystal particles having a mean particle size of 1 μm aggregated into spheres, and the particle size distribution of the crystal particles was directly transferred onto the spheres to be the surface roughness thereof. Next, the powder was heated (fired) at 1000°C for 3 hours to obtain surface-smoothed, spherical sintered ferrite particles. Next, these were washed by stirring them twice each for 20 minutes in ion-exchanged water of which the overall amount was 30 times by weight of the particles, and then dewatered and dried, thereby producing spherical sintered ferrite particles b having a soluble ion content of at most 5 ppm. Through X-ray diffractionmetry, the crystal structure of the particles was a spinel structure.

Production of Spherical Sintered Ferrite Particles c to k

The starting powder, the mean particle size and the composition of the ferrite crystal particles, the slurry concentration, and the dilution ratio of washing water were varied as in Table 1 mentioned below. Except these, the same process as that for the above-mentioned spherical sintered ferrite particles a or b was employed to produce spherical sintered ferrite particles c to k. Through X-ray diffractionmetry, the crystal structure of all these particles was a spinel structure.

The spherical sintered ferrite crystals h were not washed with water. In producing the spherical sintered ferrite

particles e, g, j and k, not only the slurry concentration was varied but also the mean particle size was controlled through classification.

The conditions in producing the spherical sintered ferrite particles a to k are shown in Table 1 below. The physical properties of the obtained, spherical sintered ferrite particles a to k were measured according to the methods mentioned below, and the data are shown in Table 2 below. The production method (a) in Table 1 means that the particles were produced according to the same method as that for producing the spherical sintered ferrite particles a; and the production method (b) means that the particles were produced according to the same method as that for producing the spherical sintered ferrite particles b. In the production method (a), the mean particle size indicates the particle size of the starting powder; and in the production method (b), the mean particle size indicates the mean particle size of the ferrite crystal particles.

Observation of Particle Morphology

Using a scanning electronic microscope (Hitachi's S-800), the particle morphology was observed.

Determination of Mean Particle Size and Particle Size Distribution

The mean particle size and the particle size distribution were determined according to a dry method, using a laser-diffractometric particle size analyser (Sympatec's

HELOS & RODOS). The particle size is based on the particle volume; and the mean particle size is a 50 % particle size. The dispersion air pressure was set at 300 Pa; the dispersion time was from 1.5 to 4 seconds; and the permeability was selected from a range of from 2 to 50 % for good reproducibility.

Determination of Pore Volume

Using a mercury penetrator Autopore 922 (by Shimadzu), the pore volume was determined.

Determination of BET Specific Surface Area

Using a full-automatic surface area meter, 4-Sorb by Yuasa-Ionics, the BET specific surface area was determined according to a nitrogen adsorption process.

Determination of Soluble Ion Amount

In a Teflon® pressure container, 5 g of pure water was added to 5 g of a test sample, and sealed up. This was extracted at 121°C for 20 hours and then cooled, and the resulting extract was analyzed through ion chromatography (Nippon Dionex's DS-500 and DS-AQ) to thereby identify the ion species and determine their amount.

Table 1

Spherical Sintered Ferrite Particles	Production Method	Mean Particle Size of Starting Powder/Crystal Particles	Production Condition										Slurry Concentration	Dilution Ratio of Washing water
			Composition											
			Starting Components (mol%)							M/Fe				
			Fe ₂ O ₃	NiO	CuO	ZnO	MnO	MgO	molar ratio					
a	(a)	0.2	48.0	15.0	12.0	25.0	-	-	-	1/1.85	60	30		
b	(b)	2.1	48.0	15.0	12.0	25.0	-	-	-	1/1.85	75	30		
c	(a)	5.8	48.0	15.0	12.0	25.0	-	-	-	1/1.85	75	40		
d	(b)	7.1	48.0	15.0	12.0	25.0	-	-	-	1/1.85	75	40		
e	(b)	2.1	48.0	15.0	12.0	25.0	-	-	-	1/1.85	50	30		
f	(b)	1.3	44.2	32.0	4.9	18.9	-	-	-	1/1.58	60	30		
g	(b)	2.1	48.0	15.0	12.0	25.0	-	-	-	1/1.85	80	20		
h	(b)	2.1	48.0	15.0	12.0	25.0	-	-	-	1/1.85	60	-		
i	(a)	0.5	47.0	-	-	18.0	5.0	30.0	1/1.77	70	30			
j	(a)	0.2	48.0	15.0	12.0	25.0	-	-	1/1.85	75	30			
k	(a)	0.2	48.0	15.0	12.0	25.0	-	-	1/1.85	50	30			

Table 2

Spherical Sintered Ferrite Particles	Properties of Spherical Sintered Ferrite Particles						
	Mean Particle Size	Pore Volume	BET Specific Surface Area	Soluble Ions (ppm)*			
	μm	liter/kg	m^2/g	Na^+	PO_4^{3-}	Cl^-	total
a	27	0.035	0.03	0	0	0	0
b	28	0.040	0.03	0	0	0	0
c	30	0.26	0.24	4	3	2	9
d	32	0.28	0.22	4	2	3	9
e	9	0.020	0.04	0	0	0	0
f	28	0.032	0.03	0	0	0	0
g	53	0.045	0.02	1	0	0	1
h	28	0.032	0.02	12	8	9	29
i	28	0.036	0.02	0	0	0	0
j	40	0.025	0.03	0	0	0	0
k	12	0.039	0.09	0	0	0	0

*: The value lower than the detection limit is 0; and the data are summed up to be the total.

Examples 1 to 8, Comparative Examples 1 to 6

Using biphenyl-type epoxy resin (softening point 105°C, epoxy equivalent 192), phenolaralkyl resin (softening point 60°C, hydroxyl equivalent 169), a flame retardant of bromobisphenol A-type epoxy resin (softening point 77°C, epoxy equivalent 465), antimony trioxide, tetraphenylphosphonium tetraphenylborate, carbon black, a silane coupling agent of γ -glycidoxypentyltrimethoxysilane, polyethylene wax, spherical silica powder α (spherical fused silica, mean particle size 8.0 μm , largest particle size 9.0 μm), and spherical silica powder β (spherical fused silica, mean particle size 1.5 μm , largest particle size 1.9 μm), and using the above-mentioned spherical sintered ferrite a to k, these were blended in a ratio as in Table 3 and Table 4 below. In Examples 4, 5, 7, 8, two types of spherical sintered ferrite particles each having a different mean particle size were previously mixed and used. The particle size distribution of the mixed spherical sintered ferrite particles in Example 5 is shown in Fig. 3. In Fig. 3, peaks are seen at around 10 μm and around 30 μm . Similarly, the particle size distribution of the particles in Examples 4, 7 and 8 was also determined. As a result, in Example 4, the particle size distribution had a peak at around 10 μm and around 30 μm . In Example 7, the particle size distribution had a peak at around 12 μm and around 40 μm . In Example 8, the particle size distribution had a peak at around 12 μm and around 30 μm .

Next, the mixture was melt-mixed with a hot roll heated at 85 to 110°C, for 3 minutes, and then cooled, and thereafter passed through a 10-mesh screen to produce a powdery resin composition for semiconductor encapsulation.

Table 3

		Filler Constitution in Resin Composition for Semiconductor Encapsulation														
		Spherical Sintered Ferrite Particles (vol.%)													Spherical Silica (vol.%)	
		a	b	c	d	e	f	g	h	i	j	k	total	α	β	total
Example	1	40	-	-	-	-	-	-	-	-	-	-	40	8.6	17.4	26.0
	2	-	60	-	-	-	-	-	-	-	-	-	60	3.3	6.7	10.0
	3	-	-	-	-	-	40	-	-	-	-	-	40	8.6	17.4	26.0
	4	-	40	-	-	20	-	-	-	-	-	-	60	-	6.7	6.7
	5	-	56	-	-	10	-	-	-	-	-	-	66	-	4.0	4.0
	6	-	-	-	-	-	-	-	-	40	-	-	40	8.6	17.4	26.0
	7	-	-	-	-	-	-	-	-	-	35	15	50	-	16.0	16.0
	8	-	43	-	-	-	-	-	-	-	-	13	56	-	15.0	15.0

Table 4

		Filler Constitution in Resin Composition for Semiconductor Encapsulation													
		Spherical Sintered Ferrite Particles (vol.%)												Spherical Silica (vol.%)	
		a	b	c	d	e	f	g	h	i	j	k	total	α	β total
Comparative Example	1	-	-	40	-	-	-	-	-	-	-	-	40	8.6	17.4 26.0
	2	-	-	-	40	-	-	-	-	-	-	-	40	8.6	17.4 26.0
	3	-	70	-	-	-	-	-	-	-	-	-	70	-	-
	4	-	-	-	-	-	-	40	-	-	-	-	40	8.6	17.4 26.0
	5	-	-	-	-	-	-	-	40	-	-	-	40	8.6	17.4 26.0
	6	-	32	-	-	-	-	-	-	-	-	-	32	-	-

Formation of Test Pieces

Molded samples for measuring the magnetic property and the dielectric property thereof were formed as follows: The above-mentioned, powdery resin composition for semiconductor encapsulation was molded into tablets having a diameter of 35 mm under a condition of molding pressure 6.86 MPa × mold temperature 175°C × molding time 2 minutes, and then cured under a condition of temperature 175°C × 5 hours. The thus-molded tablets were cut into cylindrical doughnut-shaped test pieces having an outer diameter of 7 mm, an inner diameter of 3 mm and a thickness of 2 mm, using an ultrasonic cutter.

Determination of Magnetic Property and Dielectric Property

The doughnut-shaped test piece was set on Hewlett-Packard's Network Analyzer 8702D, and its magnetic property and dielectric property were determined according to a coaxial tube process under a condition of 1 GHz.

Determination of Melt Viscosity

Using a vertical flow tester (Shimadzu's Model CFT500), the melt viscosity of the powdery resin composition for semiconductor encapsulation was determined at 175°C.

Determination of Molding Burr

Using a mold for determination of molding burr (with a clearance of from 5 to 20 μm), the length of the resin burr having leaked out of the cavity was measured with calipers.

Accelerated Reliability Test

Using the powdery resin composition for semiconductor encapsulation, a semiconductor element was transfer-molded (condition: $175^{\circ}\text{C} \times 2$ minutes, $175^{\circ}\text{C} \times 5$ hours post-curing) to
5 fabricate a semiconductor device. The semiconductor device (package) is a 16-pin dual in-line package (DIP), in which the semiconductor element was mounted on Si via an insulating film, with aluminium wiring formed thereon. Thus fabricated, 10 semiconductor device samples of each of Examples and Comparative
10 Examples were subjected to a pressure cooker bias test (PCBT). In PCBT, a bias voltage of 5 V was applied to the sample in a high-temperature high-humidity tank of $130^{\circ}\text{C} \times 85\%$ RH, and the time taken until the aluminium wiring broke was determined. The samples for which more than 100 hours were taken before 50 %
15 of the semiconductor element wiring broke are good (A); those for which less than 100 hours were taken before 50 % of the semiconductor element wiring broke are not good (B); and those for which less than 40 hours were taken before 50 % of the semiconductor element wiring broke are worse (C).

20 The test results of the samples are given in Table 5 and Table 6 below.

Table 5

	Complex Magnetic Permeability μ'' (1 GHz)	Melt Viscosity (dPa·s/175°C)	Molding Burr (mm)	Accelerated Reliability Test
Example	1	325	2 mm or less	A
	2	343	2 mm or less	A
	3	330	2 mm or less	A
	4	361	2 mm or less	A
	5	390	2 mm or less	A
	6	335	2 mm or less	A
	7	330	2 mm or less	A
	8	330	2 mm or less	A

Table 6

	Complex Magnetic Permeability μ'' (1 GHz)	Melt Viscosity (dPa-s/175°C)	Molding Burr (mm)	Accelerated Reliability Test	
Comparative Example	1	1.3	412	2 mm or less	B
	2	1.3	419	2 mm or less	B
	3	3.1	431	2 mm or less	A
	4	1.3	190	3.5 mm	A
	5	1.3	340	2 mm or less	C
	6	0.9	141	5.7 mm	A

From the results in Table 5 and Table 6 above, it is understood that the resin composition samples for semiconductor encapsulation of Examples, to which were added spherical sintered ferrite particles having a soluble ion content of at most 5 ppm, having a mean particle size of from 10 to 50 μm and having a spinel structure, have a large complex magnetic permeability and good electromagnetic wave shieldability. In addition, these resin composition samples have a suitable melt viscosity of from 300 to 400 dPa·s, therefore having good flowability. Moreover, the molding burr from these resin compositions is small, and these resin composition had a good result in the accelerated reliability test. In particular, the resin composition samples for semiconductor encapsulation of Examples 4 and 5, to which were added spherical sintered ferrite particles having a spinel structure and having, in the particle size distribution thereof, a peak in a particle size range of from 5 to 15 μm and in a particle size range of from 20 to 50 μm , have an especially large complex magnetic permeability and especially good electromagnetic wave shieldability. The resin compositions of Examples 7 and 8 have a low melt viscosity relative to the complex magnetic permeability thereof.

As opposed to these, the comparative resin composition samples, to which were added spherical sintered ferrite particles not falling within the scope of the spherical sintered ferrite particles of the invention, are problematic in that their

reliability is poor, their melt viscosity is too high and they are hardly applicable to continuous production, or their melt viscosity is too low and their molding burrs are great, or they could not ensure the necessary magnetic loss μ'' .

5

Industrial Applicability

The present invention provides spherical sintered ferrite particles useful as a filler for a resin composition for semiconductor encapsulation, a resin composition for
10 semiconductor encapsulation comprising it, which has good electromagnetic wave shieldability, good moldability and high reliability, and a semiconductor device encapsulated with the resin composition.

Claims

1. Spherical sintered ferrite particles' having the following properties (a) to (c):

(a) the water soluble ion content of the particles in 5ppm or less;

(b) the mean particle size of the particles is from 10 to 50 μm ;

(c) the crystal structure of the particles by X-ray diffractiometry is a spinel structure.

(d) the particle size distribution of the spherical sintered ferrite particles has a peak in each of a particle size range of from 5 to 15 μm and a particle size range of from 20 to 50 μm .

2. Spherical sintered ferrite particles as claimed in claim 1, which are an oxide of Fe and at least one metal element M selected from the group consisting of Mg, Zn, Ni, Mn and Cu.

3. Spherical sintered ferrite particles as claimed in claim 2, wherein the molar ratio of the metal element M to Fe (M/Fe) constituting the spherical sintered ferrite particles is within a range of $M/\text{Fe} = 1/1.57$ to $1/2.17$.

4. Spherical sintered ferrite particles as claimed in any one of claims 1 to 3, which have a specific surface area by a BET method of from 0.02 to 0.1 m^2/g .

5. Spherical sintered ferrite particles as claimed in any one of claims 1 to 4, which have a pore volume by a mercury penetration method of 0.2 liter/kg or less.

6. A resin composition for semiconductor encapsulation, which comprises a filler containing the spherical sintered ferrite particles of any one of claims 1 to 5, and silica particles.

7. The resin composition for semiconductor encapsulation as claimed in claim 6, wherein the proportion of the filler is from 65 to 80 % by volume of the resin composition.

8. The resin composition for semiconductor encapsulation as claimed in claim 6 or 7, wherein the proportion of the spherical sintered ferrite particles in the filler is at least 50 % by volume of the filler.

9. The resin composition for semiconductor encapsulation as claimed in claim 8, wherein the blend constitution of the filler meets the following (d1) to (d3):

(d1) the silica particles having a mean particle size of from

5 to 15 μm account for from 4 to 30 % by volume of the filler;

(d2) the spherical sintered ferrite particles having a mean particle size of from 20 to 50 μm account for from 50 to 93 % by volume of the filler;

(d3) the silica particles having a mean particle size of from 0.2 to 2 μm account for from 3 to 30 % by volume of the filler.

10. The resin composition for semiconductor encapsulation as claimed in claim 8, wherein the blend constitution of the filler meets the following (d4) to (d6):

(d4) the spherical sintered ferrite particles having a mean particle size of from 5 to 15 μm account for from 4 to 30 % by volume of the filler;

(d5) the spherical sintered ferrite particles having a mean particle size of from 20 to 50 μm account for from 50 to 93 % by volume of the filler;

(d6) the silica particles having a mean particle size of from 0.2 to 2 μm account for from 3 to 30 % by volume of the filler.

11. The resin composition for semiconductor encapsulation as claimed in any one of claims 6 to 10, wherein the silica particles are spherical silica particles.

12. The resin composition for semiconductor encapsulation as claimed in any one of claims 6 to 11, which contains an epoxy resin and a phenolic resin-based curing agent.

13. The resin composition for semiconductor encapsulation as claimed in claim 12, which contains a curing accelerator along with the epoxy resin and the phenolic resin-based curing agent.

14. A semiconductor device produced by encapsulating a semiconductor element with the resin composition for semiconductor encapsulation of any one of claims 6 to 13.